

PATENT APPLICATION
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q87267

Masahiko HATA

Appln. No.: 10/530,562

Group Art Unit: 1722

Confirmation No.: 8996

Examiner: Felisa Carla HITESHEW

Filed: April 7, 2005

For: METHOD FOR PRODUCING THIN FILM CRYSTAL WAFER, SEMICONDUCTOR
DEVICE USING THE SAME AND METHOD FOR PRODUCING THE
SEMICONDUCTOR DEVICE

PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of time of
three months, extending the time for responding to the Office Action of May 2, 2007 to
November 2, 2007.

The statutory fee of **\$1,050.00** is being charged to Deposit Account No. 19-4880 via EFS
Payment Screen. The USPTO is also directed and authorized to charge all required fees, except
for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit
any overpayments to said Deposit Account.

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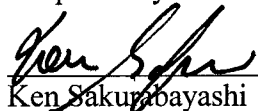
WASHINGTON OFFICE

23373

CUSTOMER NUMBER

Date: October 31, 2007

Respectfully submitted,



Ken Sakurabayashi
Registration No. 58,490